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Dated: January 12, 2005

Signature: 

Michael R. Hull

Docket No.: 29926/39505
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Young-Soo Kim

Application No.: 10/615,038

Confirmation No.: 3909

Filed: July 8, 2003

Art Unit: 2824

For: ATOMIC LAYER DEPOSITION OF
TITANIUM NITRIDE USING BATCH TYPE
CHAMBER AND METHOD FOR
FABRICATING CAPACITOR BY USING THE
SAME

Examiner: Bradley Smith

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This paper is filed in response to the office action mailed on September 29, 2004. Please amend the above-identified patent application as follows.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Remarks/Arguments begin on page 6 of this paper.